



501.30598CC3

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): MORIOKA, et al  
Serial No.: 09/805,188  
Filed: March 14, 2001  
For: METHOD AND APPARATUS FOR ANALYZING THE STATE  
OF GENERATION OF FOREIGN PARTICLES IN  
SEMICONDUCTOR FABRICATION PROCESS  
Group: 2877  
Examiner: T. Nguyen

**AMENDMENT AFTER FINAL ACTION**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

January 23, 2004

Sir:

In response to the Office Action September 23, 2003, the following amendments and remarks are respectfully submitted in connection with the above-identified application, as listed below and as set forth on the following pages:

Amendment of the Claims; and

Remarks are included following the amendments.

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